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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of

: ATTN: BOX RCE

Yoshio YANASE et al.

: Confirmation No. 6344

Serial No. 09/856,982

: Atty Docket No. 2001_0615A

Filed May 30, 2001

: Group Art Unit 2877✓

METHOD FOR INSPECTING
SEMICONDUCTOR WAFER SURFACE

: Examiner Sang H. Nguyen

PATENT OFFICE FEE TRANSMITTAL FORM

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

Attached hereto is a check in the amount of \$1,190.00 to cover Patent Office fees relating to filing the following attached papers:

Request for Continued Examination (RCE) \$770.00

Petition for Extension of Time \$420.00

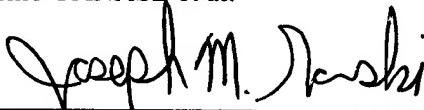
A duplicate copy of this paper is being submitted for use in the Accounting Division, Office of Finance.

The Commissioner is authorized to charge any deficiency or to credit any overpayment associated with this communication to Deposit Account No. 23-0975, with the EXCEPTION of deficiencies in fees for multiple dependent claims in new applications.

Respectfully submitted,

Yoshio YANASE et al.

By



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[Check No. 58460]
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